



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

In Reply to the Application of:

David Skee

Serial No.: 10/572,860

Filed: March 22, 2006

Atty. File No.: 1595 WO/US

Title: Alkaline, Post Plasma Etch/Ash Residue  
Removers and Photoresist Stripping  
Compositions Containing Metal-Halide  
Corrosion Inhibitors

) Group Art Unit: 1764

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) Examiner: Not yet assigned

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CERTIFICATE OF MAILING

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*Michelle DeCorte*  
MICHELLE DE CORTE

SECOND SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In accordance with duties imposed by 37 CFR §1.56 and means for complying therewith according to 37 CFR §§1.97-1.98, the references listed on the attached Form PTO/SB/08A are called to the attention of the US Patent & Trademark Office in relation to the present application.

Each item of information contained in the attached Form PTO/SB/08A was first cited in a communication from a foreign patent office (China) in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

No representation is made that the cited references are the only art or that the cited references represents the best art. The Examiner is urged to consider all of the cited references and to make an independent evaluation of the teachings and materiality of each.

Since this correspondence is being submitted after a first Office Action pursuant to § 1.97 (c) (1), it is believed that no fee is due. However, if a fee is required for entry of this correspondence, please charge Deposit Account No. 13-1160.

Respectfully submitted,

*Christine Rebman Cooke*

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